



FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICE

ATTORNEY DOCKET NO. 3948/USA/ETCH/SILICON/JB1

SERIAL NO.:  
09/379,753**LIST OF ART CITED BY APPLICANT**  
(Use several sheets if necessary)

APPLICANT: Grimbergen

FILING DATE: 8/24/1999

GROUP: 1763

**U.S. PATENT DOCUMENTS**

Examiner Initial		DOCKET NUMBER							DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
<i>RF</i>	AA	4	1	8	3	6	7	2	01/15/80	Raber, et al.	356	601	
	AB	4	2	8	9	1	8	8	09/15/81	Muzutani, et al.	216	60	
	AC	4	4	9	1	4	9	9	01/01/85	Jerde, et al.	216	60	
	AD	4	9	2	7	7	8	5	05/22/90	Theeten, et al.	438	9	
	AE	5	2	0	8	6	4	4	05/04/93	Litvak, et al.	356	72	
	AF	5	3	6	2	9	6	9	11/08/94	Glenn	250	559.18	
	AG	5	4	0	5	4	8	8	04/11/95	Dimitrelis, et al.	216	60	
	AH	5	5	6	5	1	1	4	10/15/96	Saito, et al.	216	60	
<i>V</i>	AI	5	7	3	8	7	5	6	04/14/98	Liu	216	60	
	AJ												
	AK												

**FOREIGN PATENT DOCUMENTS**

		DOCKET NUMBER							DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
													YES	NO
<i>RF</i>	AL	0	8	4	1	6	8	2	05/13/98	European Patent			x	
<i>V</i>	AM	9	4	2	5	9	7	7	11/10/94	PCT			x	
	AN													
	AO													
	AP													

**OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)**

<i>RF</i>	AQ	Böbel, et al, "In situ film-thickness and temperature monitor", SOLID STATE TECHNOLOGY, vol. 37, no. 8, 08/01/94, pp.55,56,59, Tulsa OK, USA.
<i>RF</i>	AR	European Search Report dated December 29, 2000.
	AS	

EXAMINER

*Andy Zenger*

DATE CONSIDERED

*4/29/01*

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.